



Manipulated Bessel Beams and their Applications

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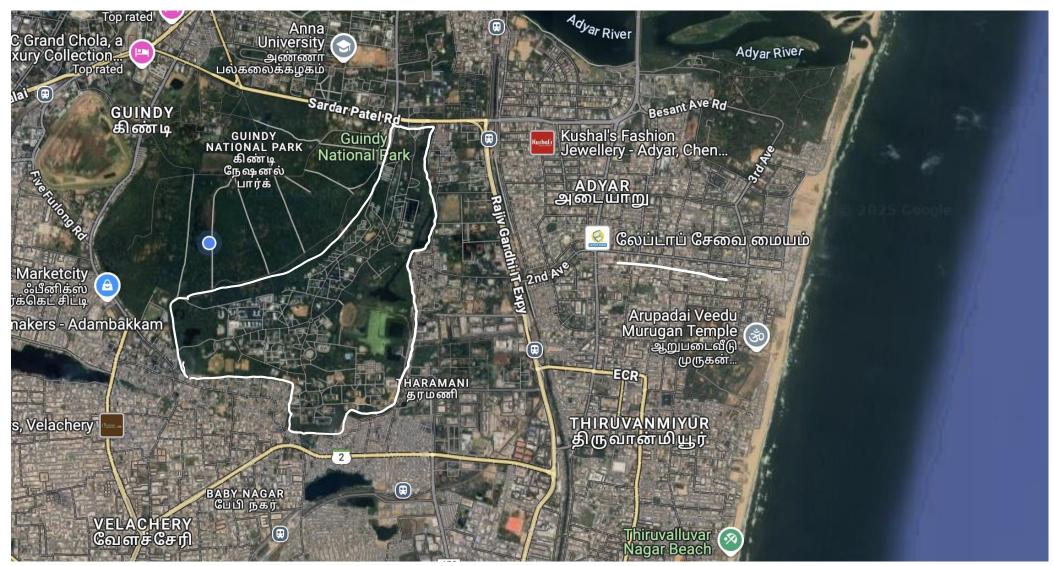






IIT Madras: A forest in the middle of the city







Inside the forest

photonics IMDIAN INSTITUTE OF TECHNOLOGY MADDAS

 Centre for teaching, research and industrial consultancy

 A residential institute with nearly 700 faculty, 12000 students and 1250 administrative & supporting staff

 A self-contained campus located in a beautiful 2.5 km² forested

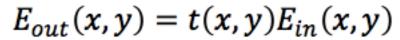
land

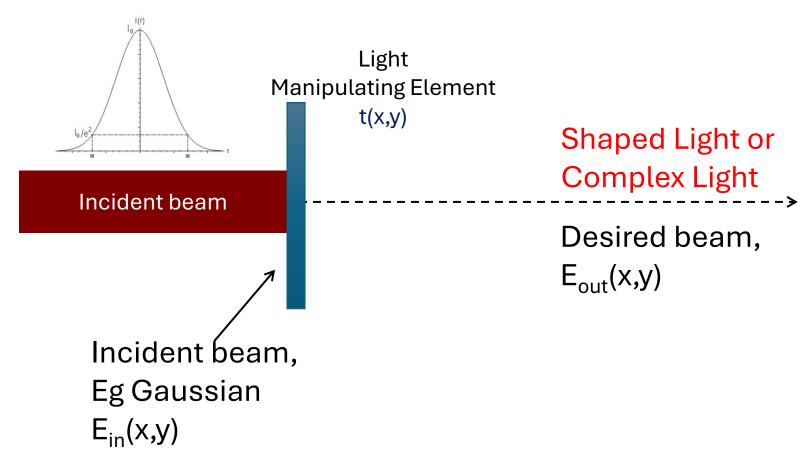






Beam Shaping









Research Questions

- What t(x,y) do we need to get a specific $E_{out}(x,y)$?
- How to design or calculate t(x,y)?
- Should the phase element be
 - Refractive
 - Diffractive
 - Meta
- What is the best way to fabricate the element?

Application: Generation of Sidelobe Suppressed Bessel Beams





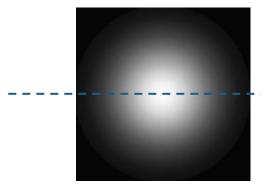
Bessel Beams

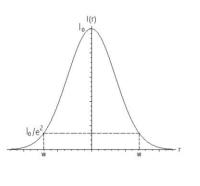


Gaussian versus Bessel Beam

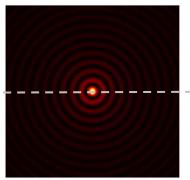




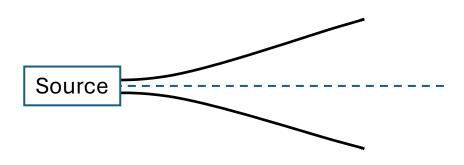




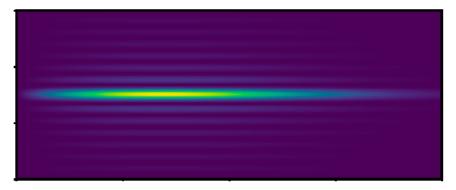
Bessel Beam Cross Section



Direction of propagation



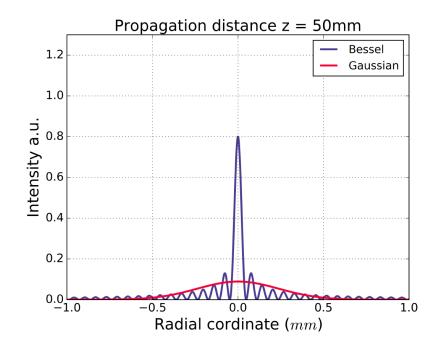
$$\psi(r,z,t) = J_0(k_r r)e^{i(k_z z - \omega t)}$$







Bessel Beam: Diffraction-free



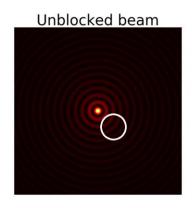


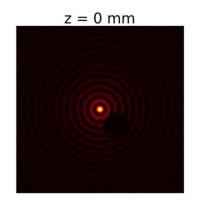


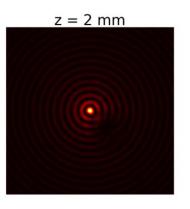
Self Healing Property

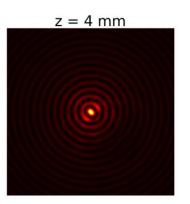
Self healing:

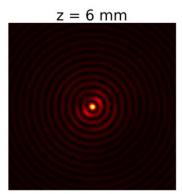
- Ability to reconstruct original shape
- Advantages:
 - Multiple particle trapping
 - Speeds up Light microscopy









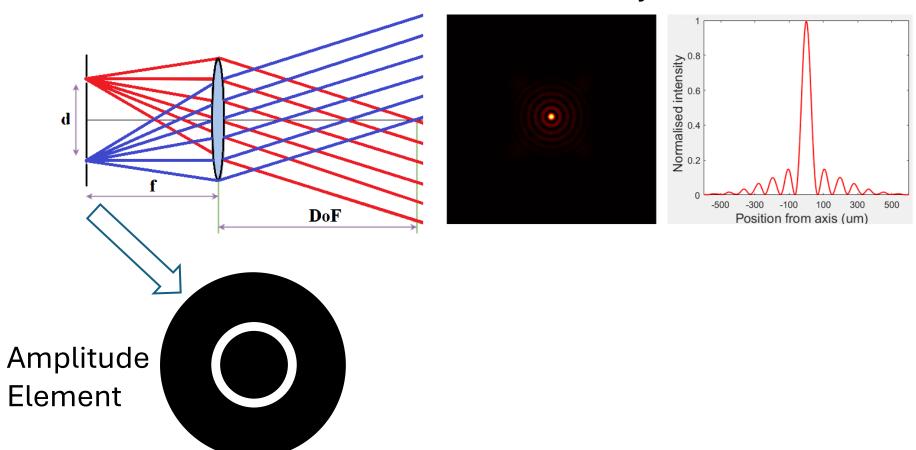














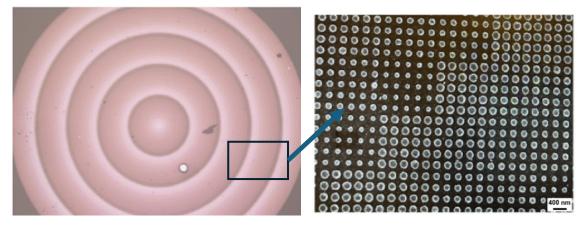
Phase Elements



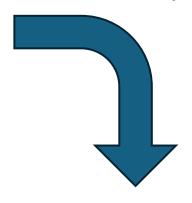
Refractive



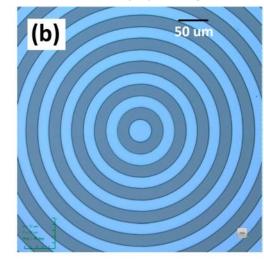
Meta-surface



Modulo 2π Operation



Diffractive







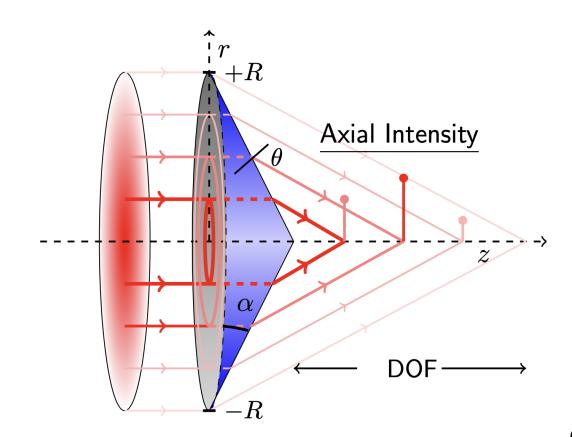
What they don't tell you about Bessel Beams

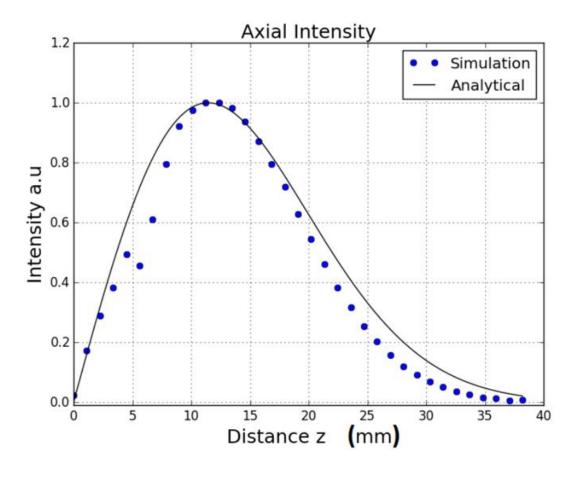
(Problem 1)





Axial Intensity





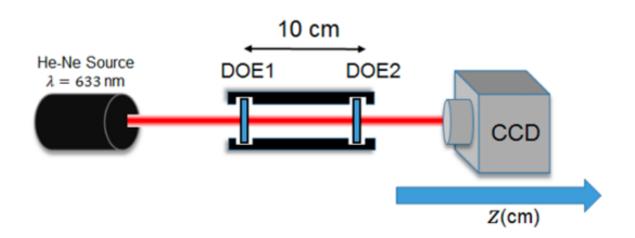
General relationship between AI(z) and $I_{in}(r)$:

$$AI(z) = MI_{in}(r)z$$
M(n, $lpha$)







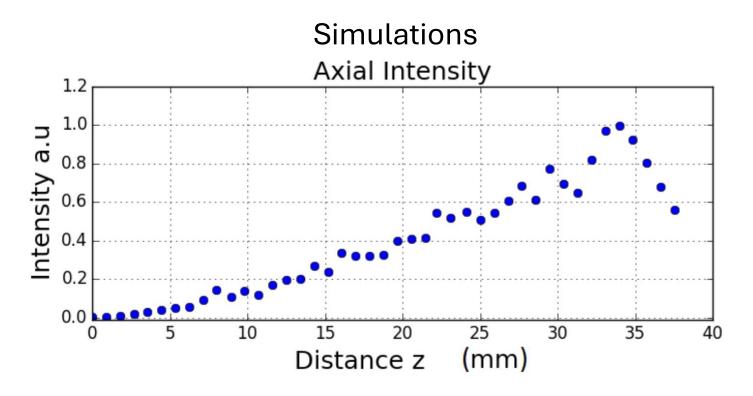


- Axicon illuminated with incident beam of desired cross section I(r)
- Fresnel integral used to compute the transverse intensity at different z distances
- DOE1 I(r)
- DOE2- Axicon



Linearly Increasing axial intensity





$$AI(z) = MI_{in}(r)z$$

$$AI(z) = az$$

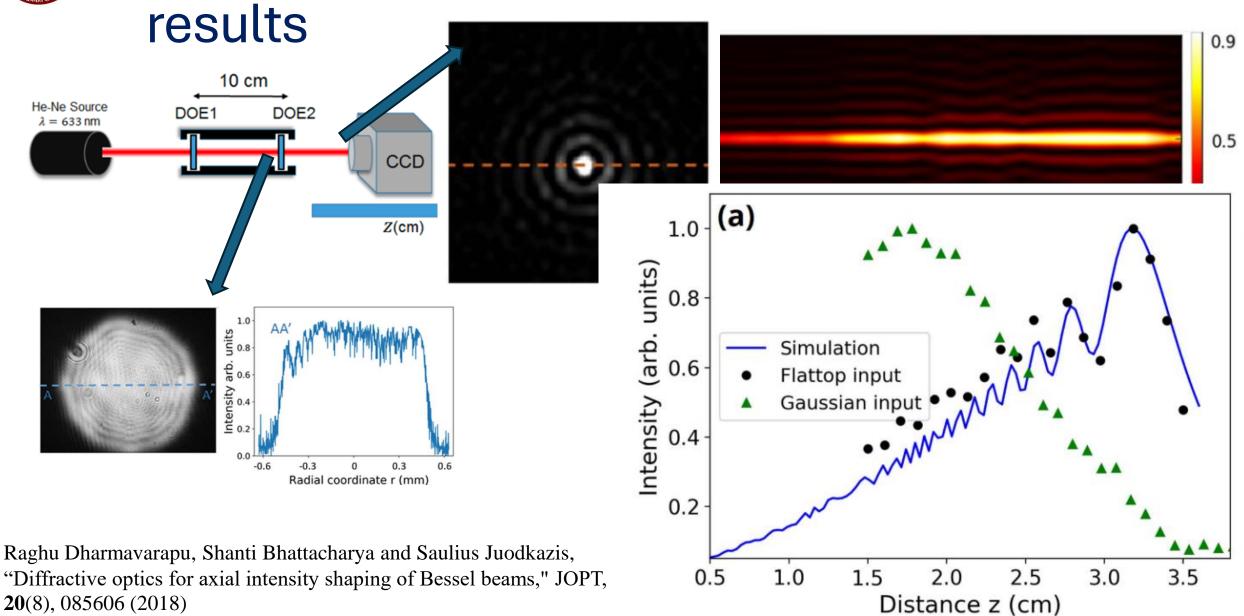


Input beam: Tophat intensity



Linearly increasing – Experimental



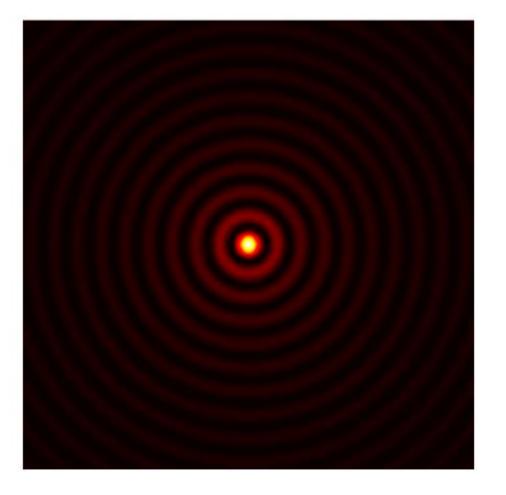








 Goal: Design a sidelobe suppressed Bessel beam



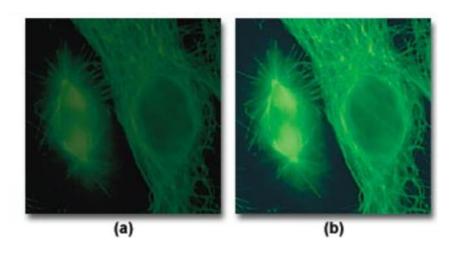




Sidelobe suppressed Bessel beams: Application

Photobleaching

Fluorophores exposed to unwanted radiation — lose ability to fluoresce.



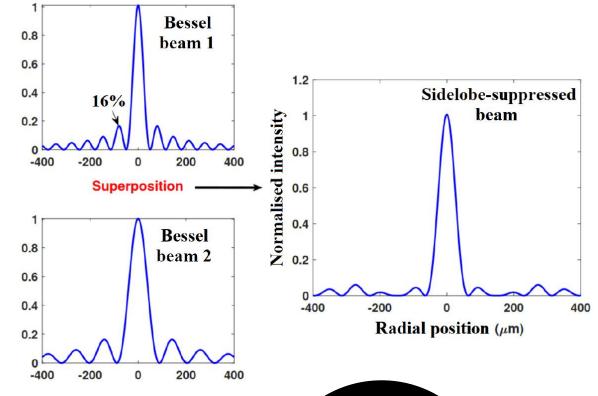
https://www.olympus-lifescience.com/en/microscope-resource/primer/photomicrography/fluorescenceerrors/

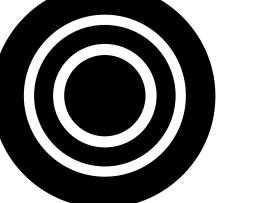




beams

- High sidelobe energy
 - first sidelobe peak intensity is 16%
- Superposition of two Bessel beams – sidelobes interfere destructively









Optimising Bessel Beam Parameters

• The superposed beam can be represented by,

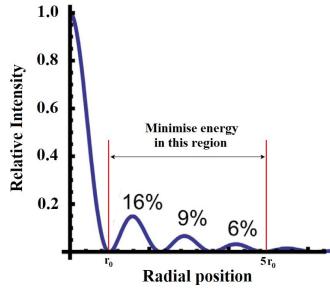
$$SP(r,z) = A_1 J_o(k_{r1}) \exp(jk_{z1}z) + A_2 J_o(k_{r2}) \exp(jk_{z2}z)$$

• The intensity of the superposed Bessel beam where k_z vectors coincide is,

$$I(r) = |A_1 J_o(k_{r1}) + A_2 J_o(k_{r2})|^2$$

• Sidelobe intensity in the desired region $(r_0 - r_1)$ is reduced by minimising the following integral

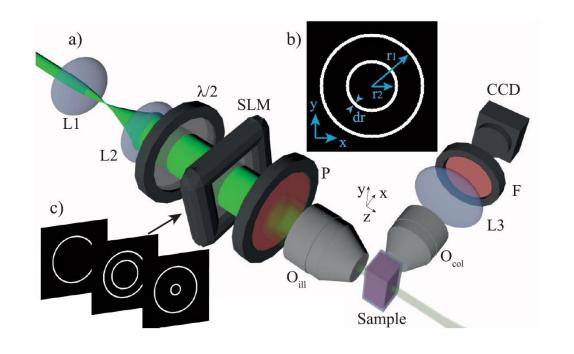
$$I = \int_{r_0}^{r_1} |A_1 J_o(k_{r1}) + A_2 J_o(k_{r2})|^2 dr$$





Sidelobe Suppressed Bessel Light Sheet





G. Di Domenico, G. Ruocco, C. Colosi, et al., "Cancellation of bessel beam side lobes for high-contrast light sheet microscopy," Sci. Rep. **8**(1), 17178 (2018).





Increasing efficiency

Bessel beams generated by annular rings

- Amplitude elements
- Poor efficiency

To improve efficiency – phase elements

- 1. Phase hologram to create the combined Bessel beams
 - Tilted plane wave added to

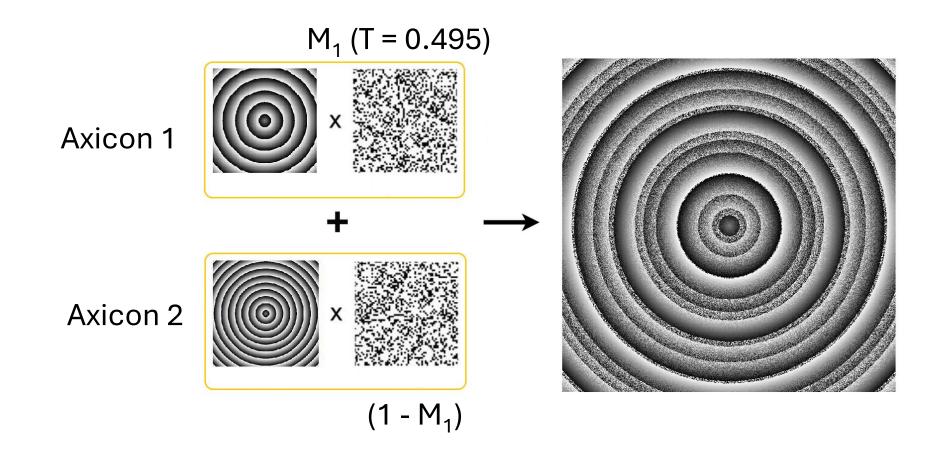
$$E(r) = A_1 J_o(k_{r1}) + A_2 J_o(k_{r2})$$

2. Multiplexing





Efficient Multiplexing of Axicons

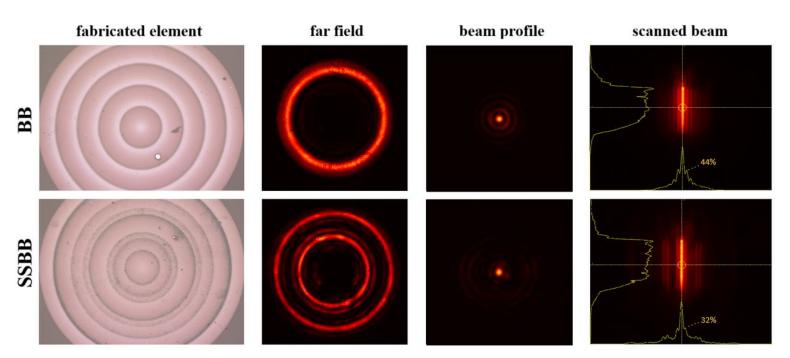


Jerin Geogy George, Kishan Dholakia, and Shanti Bhattacharya, "Generation of Bessel-like beams with reduced sidelobes for enhanced light-sheet microscopy," Opt. Continuum 2, 1649-1660 (2023)





Experimental Results

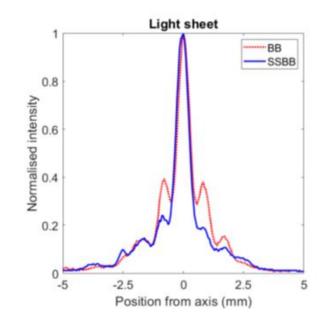


Cross-section

Bessel - experiment
SSBB - experiment
SSBB - experiment
O.4

0.2

-500
-300
-100
100
300
500
Position from axis (µm)

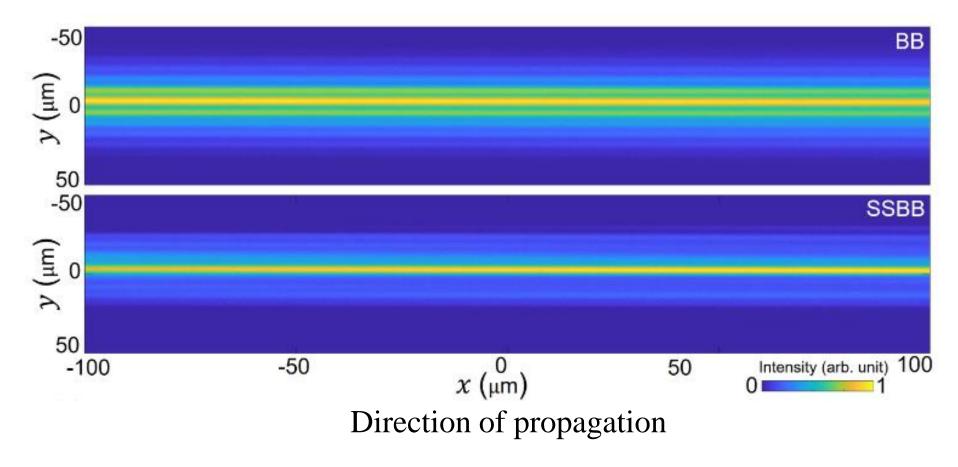


Jerin Geogy George, Kishan Dholakia, and Shanti Bhattacharya, "Generation of Bessel-like beams with reduced sidelobes for enhanced light-sheet microscopy," Opt. Continuum 2, 1649-1660 (2023)





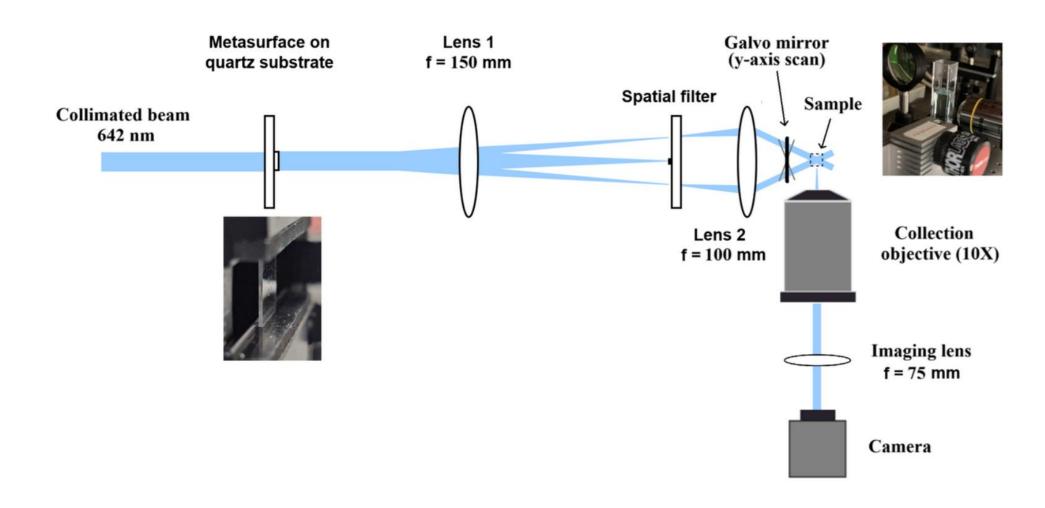
BB and SSBB (experimental) Intensity profiles in fluorescein solution







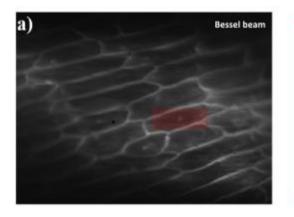


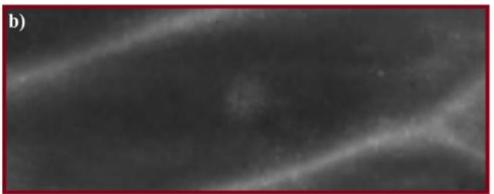




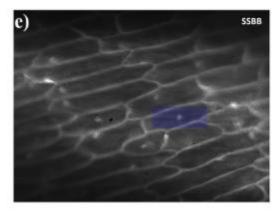
Experimental light-sheet imaging of onion epidermal cells

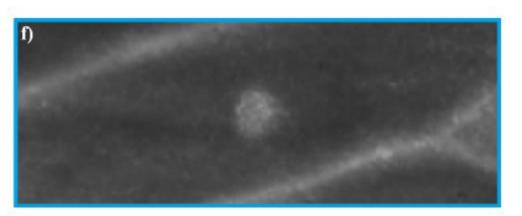






Bessel beam



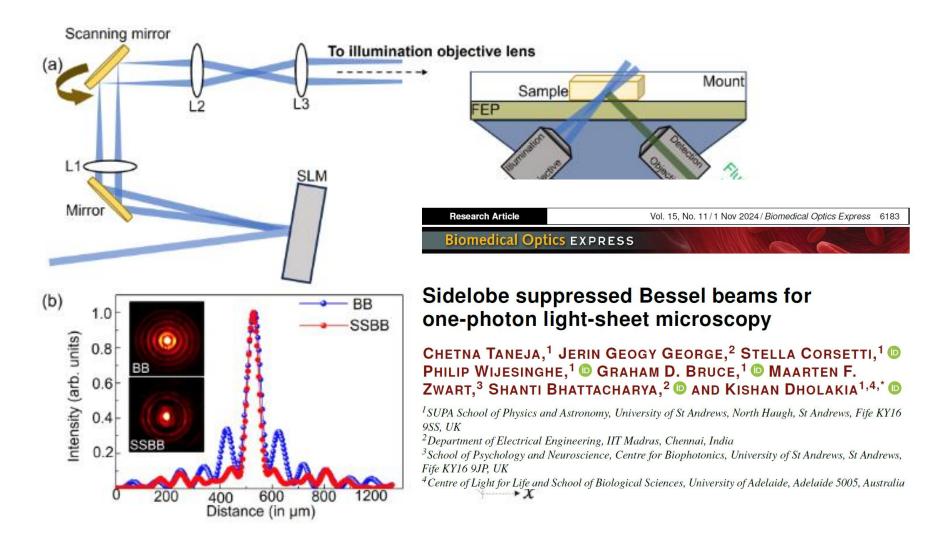


Sidelobe Suppressed Bessel beam





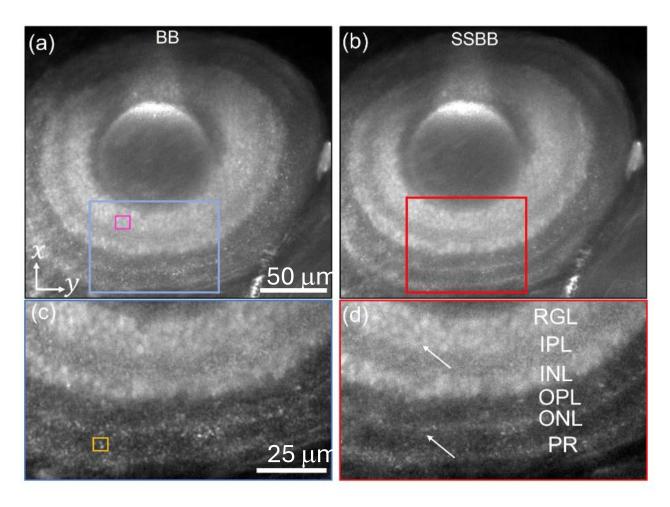
Sidelobe Suppressed Bessel Beams for LSM







Imaging GCaMP labelled cell nuclei of the zebrafish (4-5 dpf) eye



Magnified views





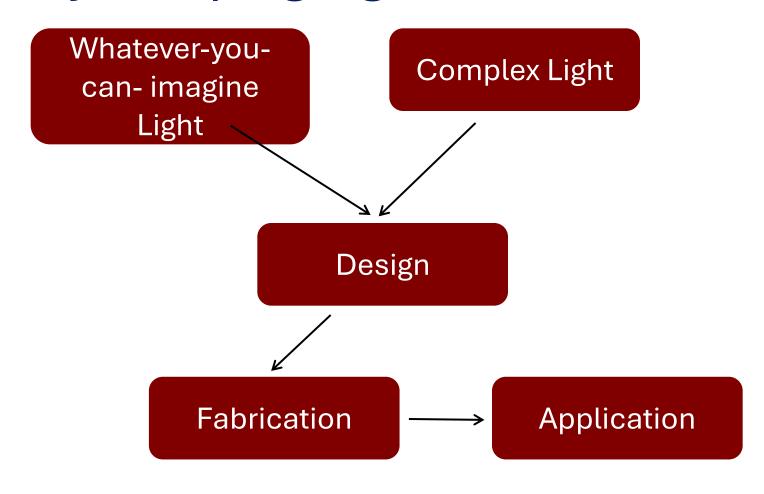
Summary: Shaping Light

- Introduction to Bessel beams
- Ways of improving them
- Applications (in imaging)





Summary: Shaping Light





Work presented today





Jerin George

Meta-optics for PSF Engineering



Raghu D

Design and
Fabrication of
Meta-optics for
Complex Light
Generation



Prof. Kishan Dholakia School of Physics and Astronomy Sir James Mackenzie Institute for Early Diagnosis Centre for Biophotonics, Univ. of St. Andrews, Scotland





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 - MeitY
 - DST
- Centre for NEMS and Nanophotonics, IIT Madras

Support from conference organisers for this trip



Thank you









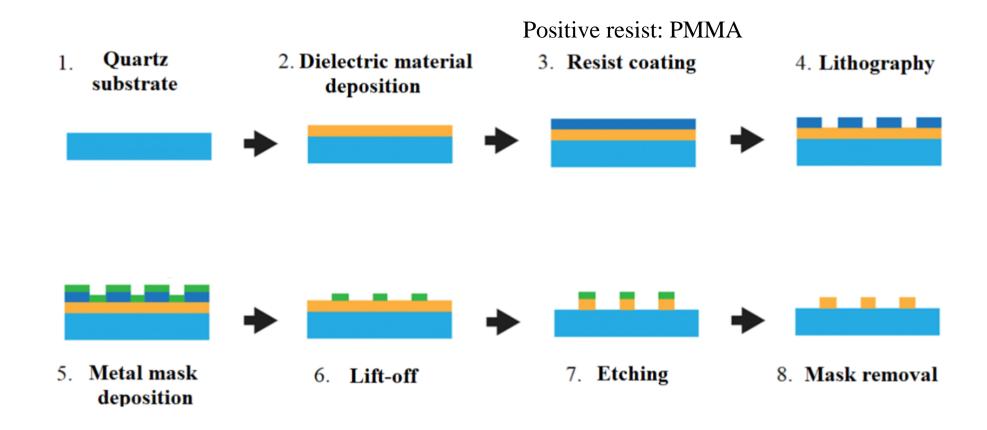
Table 1. Experimentally calculated DOFs of the BB and the SSBB light sheets compared to a theoretical Gaussian light-sheet of equal thickness. To attain the same DOF as the SSBB, the Gaussian light-sheet thickness would have to be increased to \sim 6.5 μm at the expense of axial resolution.

	ВВ	SSBB	Gaussian (Theoretical)	
			Matched thickness	Matched DOF
Thickness of light-sheet	$4.8\mu\mathrm{m}$	4.8 μm	$4.8~\mu\mathrm{m}$	6.5 μm
Depth of focus (DOF)	1.4 mm	$540\mu\mathrm{m}$	$296\mu\mathrm{m}$	$540\mu\mathrm{m}$





Fabrication – Metaoptics





Fabrication – Metaoptics



